

Abstract

Thin film piezoelectric resonator

In the layer of the cover electrode, or in an additional layer applied thereon, the resonator is provided with holes, preferably produced lithographically, or similar structures, which have a mean spacing from one another which is smaller than the provided wavelength for operating the component. These structures are preferably distributed with a uniformity sufficient to effect a uniform change in the mass of the layer per area, thus producing a specific setting of the resonant frequency/frequencies, and are preferably, on the other hand, distributed so irregularly that defraction effects are avoided.

Fig. 1